

Notice of References Cited	Application/Control No. 10/571,279		Applicant(s)/Patent Under Reexamination TAKAHASHI ET AL.	
	Examiner SUN JAE Y. LOEWE		Art Unit 1626	Page 1 of 1

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*	A	US-2004/0018192	01-2004	Wakabayashi et al.	424/144.1
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NON-PATENT DOCUMENTS

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